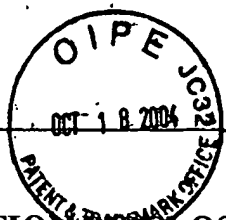


Form PTO-1449



INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

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 Applicant
Kohl, et al.

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 Group
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U.S. PATENT DOCUMENTS

Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
yct	A	2004/0,076,910	04/22/04	Rutter, Jr. et al.	430	311	04/05/03
1	B	2004/0,126,694	07/01/04	Devoe et al.	430	270.1	06/15/00
1	C	2004/0,137,728	07/15/04	Gallagher et al.	438	689	09/13/03
yct	D	6,121,340	09/19/00	Shick et al.	522	31	11/04/96

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

yct	E	WU, X. et al.: Lithographic Characteristics and Thermal Processing of Photosensitive Sacrificial Materials; Journal of the Electrochemical Society, 149, 10, G555-G561 (2002)
yct	F	WU, et al.: Photoinitiation systems and thermal decomposition of photodefinable sacrificial materials; Journal of Applied Polymer Science, Volume 88, Issue 5, 2 May 2003, Pages 1186-1195.

* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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